

**INNOVATION VENTURES** 

**AVAILABLE TECHNOLOGIES** 

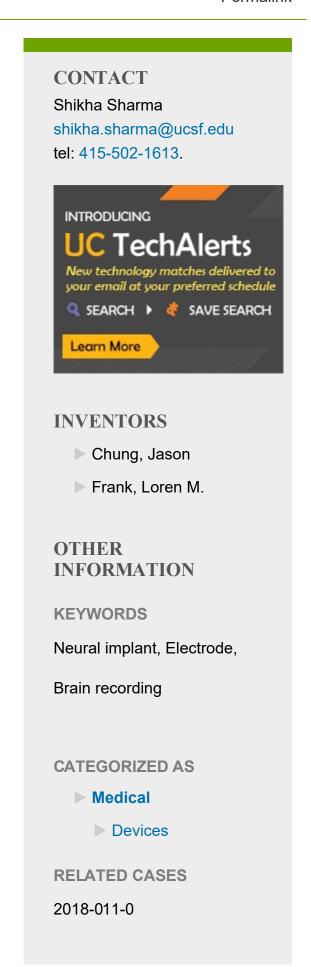
**CONTACT US** 

**Request Information** 

Permalink

## Neural Implant Platform for Direct and Large Surfacearea Access to Brain

Tech ID: 29321 / UC Case 2018-011-0



**INVENTION NOVELTY** 

This invention is a neural implantation platform permitting large scale recording of brain activity, suitable for both animals and

humans. The use of advanced silicone materials in the design allows for greater access to brain surface area than currently

existing implantation platforms.

**VALUE PROPOSITION** 

Current methods of neural implantations are limited in size and the area of recording of brain activity due to issues with stability

and heat dissipation. This design utilizes silicone gels and elastomers along with other innovations to bypass those issues and

allow for larger areas of brain to be implanted.

Advantages of Technology

Allows for large scale recording of brain activity in animals and humans

Superior heat dissipation, allowing for larger devices, covering larger surface area

Silicone elastomers seal the opening around the brain preventing cerebrospinal fluid leakage and reducing the risks of

infection, while still allowing devices to pass through

A harder silicone elastomer cap provides pressure matching normal intracranial pressure reducing brain pulsations and the

risk of herniation

Embedding of flexible material in silicone allows forces to be distributed along the length of the device providing strain relief

A protective shell covers the active electronics protecting it from impact and movement

**TECHNOLOGY DESCRIPTION** 

Researchers from University of California, San Francisco have developed a neural implant platform for direct and large-scale

access to brain. This platform is suitable for the positioning of flexible, implantable devices, such as recording electrodes or deep-

brain stimulators, both on the surface of the brain as well as within the brain under the surface.

These flexible devices are embedded in a low-viscosity silicone gel that also seals the edges of the durectomy and craniectomy.

This gel is then capped with a harder silicone elastomer to match intracranial pressure. The flexibility of the devices provides strain

relief and the silicone elastomer cap protects the active electronic components of the implantation platform.

**LOOKING FOR PARTNERS** 

To develop & commercialize the technology as the implantation platform for an implantable electronics package.

STAGE OF DEVELOPMENT

Pre-clinical

**DATA AVAILABILITY** 

Under CDA / NDA

**PATENT STATUS** 

Country	Туре	Number	Dated	Case
United States Of America	Issued Patent	11.648.394	05/16/2023	2018-011

## Additional Patent Pending

ADDRESS

UCSF
Innovation Ventures

600 16th St, Genentech Hall, S-272,
San Francisco,CA 94158

Fax:

CONNECT
Follow in Connect
Follow in Connect
Connect
Follow in Connect
Connect
Follow in Con